	Application No.	Applicant(s)
Notice of Allowability	10/615,048	BLATCHFORD, ET AL.
	Examiner	Art Unit
	Sun J. Lin	2825

-- The MAILING DATE of this communication appears on the cover sheet with the correspondence address--

All claims being allowable, PROSECUTION ON THE MERITS IS (OR REMAINS) CLOSED in this application. If not included herewith (or previously mailed), a Notice of Allowance (PTOL-85) or other appropriate communication will be mailed in due course. **THIS NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT RIGHTS.** This application is subject to withdrawal from issue at the initiative of the Office or upon petition by the applicant. See 37 CFR 1.313 and MPEP 1308.

1. ☒ This communication is responsive to *Amendment & Remarks filed on 03/01/2005.*

2. ☒ The allowed claim(s) is/are *1-17.*

3. ☒ The drawings filed on *08 July 2003* are accepted by the Examiner.

4. ☐ Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f).

    a) ☐ All   b) ☐ Some*   c) ☐ None of the:

        1. ☐ Certified copies of the priority documents have been received.

        2. ☐ Certified copies of the priority documents have been received in Application No. _____ .

        3. ☐ Copies of the certified copies of the priority documents have been received in this national stage application from the International Bureau (PCT Rule 17.2(a)).

    * Certified copies not received: _____ .

Applicant has THREE MONTHS FROM THE "MAILING DATE" of this communication to file a reply complying with the requirements noted below. Failure to timely comply will result in ABANDONMENT of this application.
THIS THREE-MONTH PERIOD IS NOT EXTENDABLE.

5. ☐ A SUBSTITUTE OATH OR DECLARATION must be submitted. Note the attached EXAMINER'S AMENDMENT or NOTICE OF INFORMAL PATENT APPLICATION (PTO-152) which gives reason(s) why the oath or declaration is deficient.

6. ☐ CORRECTED DRAWINGS (as "replacement sheets") must be submitted.

    (a) ☐ including changes required by the Notice of Draftsperson's Patent Drawing Review (PTO-948) attached

        1) ☐ hereto or 2) ☐ to Paper No./Mail Date _____ .

    (b) ☐ including changes required by the attached Examiner's Amendment / Comment or in the Office action of Paper No./Mail Date _____ .

    Identifying indicia such as the application number (see 37 CFR 1.84(c)) should be written on the drawings in the front (not the back) of each sheet. Replacement sheet(s) should be labeled as such in the header according to 37 CFR 1.121(d).

7. ☐ DEPOSIT OF and/or INFORMATION about the deposit of BIOLOGICAL MATERIAL must be submitted. Note the attached Examiner's comment regarding REQUIREMENT FOR THE DEPOSIT OF BIOLOGICAL MATERIAL.

Attachment(s)

1. ☐ Notice of References Cited (PTO-892)

2. ☐ Notice of Draftperson's Patent Drawing Review (PTO-948)

3. ☐ Information Disclosure Statements (PTO-1449 or PTO/SB/08), Paper No./Mail Date _____

4. ☐ Examiner's Comment Regarding Requirement for Deposit of Biological Material

5. ☐ Notice of Informal Patent Application (PTO-152)

6. ☐ Interview Summary (PTO-413), Paper No./Mail Date _____ .

7. ☐ Examiner's Amendment/Comment

8. ☒ Examiner's Statement of Reasons for Allowance

9. ☐ Other _____ .

Reasons for Allowance

Claims 1 – 17 are allowed over the prior art of record. An examiner's statement of reasons for allowance is given in the following:

Claim 17 is allowed due to allowable subject matter as explained in the Office Action mailed to applicants on 12/02/2004.

Claims 1 – 16 are allowed because the prior art does not teach or fairly suggest the following subject matter:

- A method for generating an optical model, comprising *generating lens aberration data according to wafer response to adjustment of a lens aberration of one or more lens aberrations of an initial lens, fitting one or more aberration functions to the lens aberration data to generate an optical model* in combination with other limitations as recited in independent **Claim 1**;

- A system for generating an optical model, comprising *a database operable to store lens aberration data associated with a wafer response to one or more lens aberrations of an initial lens; and a server coupled to the database and operable to generate lens aberration data according to the wafer response to adjustment of a lens aberration of the one or more lens aberrations, fit one or more aberration functions to the lens aberration data to generate an optical model* in combination with other limitations as recited in independent **Claim 6**;

- A logic for generating an optical model, the logic embodied in a medium and operable to *generate lens aberration data according to wafer response to adjustment of a lens aberration of one or more lens aberrations of an initial lens, fit one or more aberration functions to the lens aberration data to generate an optical model* in combination with other limitations as recited in independent **Claim 11**;

- A system for generating an optical model, comprising *means for generating lens aberration data according to wafer response to adjustment of a lens aberration of one or more lens aberrations of an initial lens, means for fitting one or more aberration functions to the lens aberration data to generate an optical model* in combination with other limitations as recited in independent **Claim 16**.

Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably

accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance".

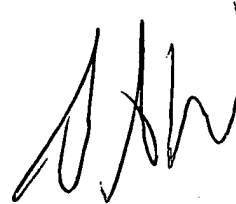## *Conclusion*

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Sun J. Lin whose telephone number is (571) 272 – 1899. The examiner can normally be reached on Monday to Friday from 9:30am to 6:30pm.

Any inquiry of a general nature or relating to the status of this application or proceeding should be directed to the receptionist whose telephone number is (703) 308-1782.

Sun J. Lin
Patent Examiner
Art Unit 2825
April 7, 2005

STACY A. WHITMORE
PRIMARY EXAMINER